

## Special Issue

# Amorphous Oxide Semiconductor-Based Memristive Devices and Thin- Film Transistors

### Message from the Guest Editors

We invite researchers and scientists to showcase their work in this Special Issue with research papers and review articles that focus on trends in AOS-based memristors, thin-film transistors, diodes and integration strategies, modelling, and simulation, from fundamental research to applications.

- Solution-based technology (coating and printing techniques)
- AOS memristive devices and systems
- neuromorphic computing with AOS-based memristors
- pattern recognition based on AOS memristors
- integration of AOS memristors with TFTs
- system-on-panel applications
- novel circuits on AOS-based memristors
- modeling and simulation of AOS processes for memristive devices
- circuit models and simulation of AOS memristors and TFTs
- resistive RAM based on AOS materials

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### Guest Editors

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### Deadline for manuscript submissions

closed (5 February 2022)



## Micromachines

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## About the Journal

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